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Geometrical Charged-Particle Optics

Second Edition

 Springer

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Preface to the Second Edition

Some errors and misprints that were found in the first edition of this work have been corrected. Although the impetus of the work is on the geometrical properties of charged-particle optics, we have included sections on the propagation of electron waves in macroscopic fields and on the Aharonov–Bohm effect in Chap. 2. The incorporation of wave-optical considerations has been necessary for deriving the resolution limit of electron microscopes and for understanding diffraction and interference phenomena utilized in electron holography.

Chapter 3 has been extended by a section on the calculation of static electromagnetic fields by means of the charge-simulation method. To elucidate the imaging properties of electron lenses in more detail, we have added in Chaps. 4 and 8 the imaging properties of the Glaser model field for a magnetic round lens because this field yields analytical expressions for the paraxial rays and the primary aberrations. Moreover, we have incorporated in Chap. 6 a section on the formation and classification of caustics because they are nowadays widely used for determining the state of alignment of aberration-corrected electron microscopes. Owing to its importance for the performance of systems corrected for primary chromatic and geometrical aberrations, we have added in Chap. 8 a section on fifth-order aberrations of multipole systems with straight axis.

We have added extensive new material to Chap. 12 and rewritten Chap. 14 on relativistic electron motion eliminating several inaccuracies. In particular, we have included aspects of the Stern–Gerlach effect and depicted Lorentz transformations within the frame of relativistic electron motion in Minkowski space. The last chapter is entirely new and discusses the effect of velocity and acceleration on the electromagnetic field of a moving charged particle. We treat this difficult problem by introducing the self-action of the particle in a covariant form. An appendix is added containing a list of symbols used frequently.

I am grateful to several readers who drew my attention to errors and misprints in the first edition and to Mrs. Anna Zilch for skilful drawing of many new figures.

Darmstadt
December 2012

Harald Rose

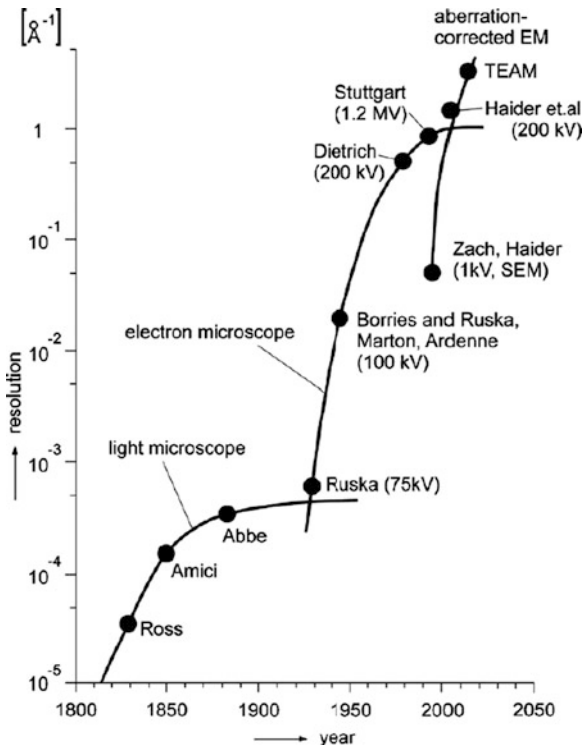
Preface to the First Edition

The resolution of any imaging microscope is ultimately limited by diffraction and can never be significantly smaller than the wavelength λ of the image-forming wave, as realized by Ernst Abbe in 1870. In a visionary statement he argued that there might be some yet unknown radiation with a shorter wavelength than that of light enabling a higher resolution at some time in the future [1]. The discovery of the electron provided such a radiation because its wavelength at accelerating voltages above 1 kV is smaller than the radius of the hydrogen atom. The wave property of the electron was postulated in 1924 by Louis de Broglie [2]. Geometrical electron optics started in 1926 when Busch [3] demonstrated that the magnetic field of a rotationally symmetric coil acts as a converging lens for electrons. The importance of this discovery was subsequently conceived by Ruska and Knoll who had the idea to build an electron microscope by combining a sequence of such lenses [4]. Within a short period of time the resolution of the electron microscope surpassed that of the light microscope, as depicted in Fig. 1. This success resulted primarily from the extremely small wavelength of the electrons rather than from the quality of standard electron lenses which limit the attainable resolution to about 100λ . Therefore, shortening the wavelength by increasing the voltage was the most convenient method for improving the resolution. However, radiation damage by knock-on displacement of atoms limits severely the application of high-voltage electron microscopes. In addition, the so-called delocalization caused by spherical aberration prevents an unambiguous interpretation of images of non-periodic objects such as interfaces and grain boundaries. The correction of the spherical aberration eliminates this deleterious effect.

The successful correction of the spherical aberration can be considered as a quantum step in the development of the electron microscope because it enables one to obtain sub-Å resolution at voltages below the threshold for atom displacement. The threshold voltage depends on the composition of the object and lies in the region between 60 to 300 kV for most materials.

At about the same time as Ruska and Knoll developed the first electron microscope with magnetic lenses, Ernst Brueche at the research department of the AEG in Berlin investigated with his collaborators A. Recknagel and H. Mahl the

Fig. 1 Increase in resolution of transmission microscopy as a function of time



properties of electrostatic round lenses. In order to obtain theoretical assistance, Brueche invited the young Otto Scherzer in 1932 to join his group. Within the short period of two years Otto Scherzer established the theoretical basis of geometrical electron optics. In 1934, he published his results together with Ernst Brueche in the first book on the subject entitled “Geometrische Elektronenoptik” [5]. Scherzer employed for his calculations the so-called trajectory method, which starts from the Newton equation of motion and the Lorentz force [6], whereas Walter Glaser applied the *Hamiltonian formalism* to electron optics to determine the motion of electrons in rotationally symmetric static electromagnetic fields [7]. This method is based on the ideas of Hamilton who showed that the properties of an optical system can be derived from a single characteristic function or eikonal. Because the two calculation procedures differ from each other, they give seemingly different integral expressions for the aberration coefficients. However, the integrals can be transformed in identical forms by partial integrations. Using this method, Scherzer transformed, in 1936, the integral expressions for the coefficients of the spherical and axial chromatic aberrations in such a form that the integrands consist of sums of positive quadratic terms, proving that these coefficients can never change sign [8]. The physical origin for this behavior is due to the fact that the static electromagnetic potentials satisfy the Laplace equation in the domain of the electron trajectories. As a consequence,

the spatial distribution of the index of refraction of electron lenses cannot be formed arbitrarily. Because the potential adopts an extremum at the boundary surfaces, the outer zones of rotationally symmetric electron lenses always focus the rays more strongly than the inner zones, causing unavoidable spherical aberration. Owing to its importance this property has been named “Scherzer Theorem”.

O. Scherzer and W. Glaser are recognized as the founders of theoretical electron optics. The subject up to 1952 was fully summarized in Glaser’s book *Grundlagen der Elektronenoptik*, which served as the standard textbook for several decades [9]. The Hamiltonian approach to electron optics was developed further by P. A. Sturrock [10]. Several other books on the subject appeared in the following years [11, 12]. In particular the treatise *Electron Optics and the Electron Microscope* by Zworykin et al. [13] and P. Grivet’s excellent *Electron Optics* [14] are milestones of the subject. The last approach covering all fields of electron optics was performed by Peter Hawkes and Erwin Kasper with their three volume treatise *Principles of Electron Optics* published in 1996 [15].

The history of electron optics is to a large extent the struggle to overcome the limitations of the resolution of electron microscopes imposed by the unavoidable spherical and chromatic aberrations of round lenses. In 1947, Scherzer demonstrated in another fundamental paper that correction of aberrations is possible by lifting any of the constraints of his theorem, either by abandoning rotational symmetry, or by introducing time-varying fields or space charges [16]. In the following decades intensive experimental efforts to compensate for the resolution-limiting aberrations by means of multipole correctors have been pursued by several groups in Germany [17], England [18] and the USA [19] with disappointing results. The attempts came to an end in the 1980s primarily due to severe problems of precisely aligning the many elements of the correctors during a period of time which is shorter than the overall stability period of the microscope. Moreover, digital processing of through-focus series provided a successful alternative solution for eliminating the spherical aberration of images a posteriori.

As a result, work on electron optics shrunk and was limited to theoretical investigations and to applications in electron lithography and to the design of electron-beam devices for the inspection of wafers [20, 21]. Owing to the advancement in technology and computer-assisted alignment, correction of the resolution-limiting aberrations became very promising again at the beginning of the 90s. In 1992, experimental work started by M. Haider at the EMBL in Heidelberg within the frame of the Volkswagen project, aimed to compensate for the spherical aberration of a transmission electron microscope (TEM) by means of a novel hexapole corrector [22]. One of the main tasks concerned the reduction of the information limit in order that the resolution was limited by the spherical aberration rather than by the incoherent aberrations resulting from instabilities. At about the same time high-performance imaging energy filters became available in commercial electron microscopes leading to a rapid growth of analytical electron microscopy [23]. The successful correction of the spherical aberration in a commercial 200 kV TEM by M. Haider et al. (1997) and by O. Krivanek et al. (1999) in a 100 kV scanning transmission electron microscope (STEM) induced a revival of electron

optics [24, 25]. In the following years, numerous new correctors compensating for chromatic and spherical aberrations were proposed as well as novel high-performance imaging energy filters and monochromators [26, 27]. The revival of electron optics culminated in the TEAM project of the US Department of Energy (DOE) aimed to realize a chromatic and spherically corrected TEM with a resolution limit of 0.5\AA .

Geometrical electron optics provides the appropriate tool for designing a large variety of other charged-particle instruments such as electron mirrors, spectrometers, time of flight analyzers, electron guns, accelerators and storage rings. Owing to the large progress in electron optics, electron holography, image formation and design of charged-particle instruments made during the last 15 years, it is impossible to treat all subjects in a single book. Therefore, we confine the content of this book to geometrical electron optics with the impetus on analytical methods for calculating the properties of charged-particle systems and methods for designing optimum electron optical instruments and elements. Diffraction effects resulting from the wave nature of the elementary particles and interactions between electrons within the beam (Boersch effect) will not be covered. Therefore, the content of this book may properly be referred to as a single particle description. Because the effect of the spin on the motion of the electron is very small, it is only treated in the chapter 14 at the end of the book.

The content of this book originated from lectures taught by the author for many years at the Technical University Darmstadt and from courses in charged-particle optics given at the Lawrence Berkeley National Laboratory (BNL) during the period 2003-2005. Therefore, particular attention has been given to the presentation of techniques which would enable the reader not only to “follow the literature” but also to perform electron optical design and calculations on his own. The degree of emphasis which each topic has is a matter of personal judgment. We have not attempted to present an encyclopedia on the subject because it is not possible to include all topics of geometrical electron optics in a single book. For example, model fields providing analytical solutions for the paraxial trajectories of electron lenses have been omitted. They are discussed in great detail in the second volume of *Principles of Electron Optics* by Hawkes and Kasper [15]. Moreover, many computer programs are nowadays available which provide solutions of the paraxial path equations for arbitrary field distributions. Most of the presented material on aberrations, systems with curved axis and aberration correctors is based on research work performed at the University of Darmstadt over a period of several decades. No attempt has been made to provide a complete bibliography. The references have been confined to those which treat specific topics in greater detail. Hence, this selection should not be judged as a ranking and I offer my apologies to the many contributors to the subject whose excellent papers have not been cited. An extensive list of references can be found in Hawkes and Kasper [15].

The book is intended as a textbook for graduate students with good mathematical background and for anyone involved in the design of charged-particle devices ranging from electron lenses to spectrometers. Practical applications of electron optics serve as illustrations of the principles under discussion. Due to the recent

progress in aberration correction, the properties of various corrector types are discussed in detail. The book contains some unpublished material on multipole systems and provides a novel analytical calculation procedure for determining the Gaussian optics and the aberrations of electron guns in the absence of space charge effects. In the last chapter we consider spin precession and radiation effects in the context of relativistic electron motion in electromagnetic fields by employing a novel covariant treatment [28]. By introducing the Lorentz-invariant universal time as independent variable, we extend the Hamilton- Jacobi formalism of classical mechanics from three to four spatial dimensions. This approach allows one to construct a proper four-dimensional covariant Lagrangian, which considers charge, gravitation and spin interactions [28].

I want to thank Dr. Weishi Wan, BNL, for numerical calculations of trajectories and Mrs. Anna Zilch for the skilful making of many drawings. Thanks are due to the members of CEOS (Heidelberg) for helpful discussions and editorial support and to Prof. E. Plies and Dr. Essers for permission to publish drawings.

Darmstadt
August 2008

Harald Rose

Contents

1	Introduction	1
2	General Properties of the Electron	5
2.1	Particle Nature of the Electron	6
2.1.1	Equation of Motion	6
2.1.2	Conservation of Energy	7
2.1.3	Hamilton's Principle	8
2.1.4	Principle of Maupertuis	11
2.1.5	Time of Flight	12
2.2	Wave Properties of the Electron	13
2.2.1	Eikonal and Fermat's Principle	14
2.2.2	Phase, Wavelength, Frequency, Phase and Group Velocity, and Index of Refraction	17
2.3	Aharanov–Bohm Effect	21
2.4	Ray Properties Associated with the Eikonal	26
2.5	Propagation of the Electron Wave in Macroscopic Fields	29
2.5.1	Propagator	30
2.5.2	Wave Propagation in the Infinite Half-Space	33
2.5.3	Fundamentals of Diffraction and Image Formation	38
2.5.4	Point Spread Function	41
3	Multipole Expansion of the Stationary Electromagnetic Field	45
3.1	Scalar Potentials	46
3.1.1	Complex Variables	47
3.1.2	Laplace Equation	49
3.1.3	Planar Fields	50
3.2	Systems with Straight Axis	52
3.2.1	Multipole Expansion of the Scalar Potential	53
3.2.2	Electrostatic Cylinder Lenses	55
3.3	Systems with Curved Axis	58
3.3.1	Recurrence Formula for the Coefficients of the Power Series Expansion	58

3.3.2	Power Series Expansion of the Electric Potential	60
3.3.3	Index of Refraction	62
3.4	Magnetic Vector Potential	63
3.4.1	Rectilinear Systems	66
3.4.2	Magnetic Fields with Special Symmetry	67
3.4.3	Systems with Curved Axis	69
3.5	Integral Representation of the Multipole Components of the Potential	71
3.6	Potentials of Simple Systems	72
3.6.1	Laplace Equation for Oblate Spheroidal Coordinates	73
3.6.2	Solutions with Rotational Symmetry	74
3.6.3	Multipoles	81
3.7	Charge-Simulation Method	84
3.7.1	Systems of Rotational Symmetry	86
4	Gaussian Optics	89
4.1	Paraxial Path Equation	90
4.2	Orthogonal Systems with Midsection Symmetry	98
4.3	Systems with a Straight Optic Axis	102
4.3.1	Systems with an Axis of Rotational Symmetry	102
4.3.2	Wronski Determinant	106
4.3.3	Lagrange–Helmholtz Relation	107
4.3.4	Theorem of Alternating Images	108
4.3.5	Longitudinal Magnification	111
4.3.6	Characteristic Paraxial Rays	112
4.3.7	Thin-Lens Approximation	113
4.4	Magnetic Model Lens	120
4.4.1	Condenser-Objective Lens	124
4.5	Quadrupoles	125
4.5.1	Imaging Properties of a Single Quadrupole	127
4.5.2	Quadrupole Multiplets	130
4.5.3	Strong Focusing	132
4.6	Electrostatic Cylinder Lenses	142
4.6.1	Modified Paraxial Equation	144
4.6.2	Short Cylinder Lenses	146
4.7	General Systems with Straight Axis	149
4.7.1	Inseparable Systems with Straight Axis	150
4.7.2	Generalized Helmholtz–Lagrange Relations	151
4.7.3	Imaging Properties	154
4.7.4	Paraxial Pseudo Rays	159
4.8	Systems with Curved Axis	160
4.8.1	General Systems	161
4.8.2	Systems with Midsection Symmetry	164

4.9	Quadrupole Anastigmat	166
4.9.1	Focal Lengths of the Constituent Quadrupoles of the Anastigmat	168
4.9.2	Cardinal Elements of the Quadrupole Anastigmat	172
4.10	Variable-Axis Lens	176
4.11	Highly Symmetric Telescopic Systems	179
4.11.1	Streak-Free Beam Chopper	187
5	General Principles of Particle Motion	189
5.1	Hamiltonian Formulation	189
5.2	Lagrange Invariants	192
5.3	Liouville's Theorem	195
5.3.1	Paraxial Approximation	197
5.3.2	Abbe Sine Condition	197
5.4	Generalized Symplectic Matrices	199
5.5	Poincaré's Invariant	202
5.6	Eikonals	207
5.6.1	Mixed Eikonal and Sine Condition	210
5.6.2	Perturbation Eikonal	212
5.6.3	Integral Equations of the Path and Momentum Deviations	220
5.7	Poisson Brackets	221
6	Beam Properties	223
6.1	Brightness	224
6.2	Emittance	227
6.2.1	Paraxial Approximation	228
6.2.2	Matching	232
6.3	Propagation of Beam Intensity	233
6.4	Caustics	234
6.4.1	Determination of the Caustic	235
6.4.2	Formation of the Caustic in Free Space	236
6.4.3	Classification of the Fundamental Caustic Forms	241
6.4.4	Third-Order Elementary Caustics	243
6.4.5	Fourth-Order Elementary Caustics	246
7	Path Deviations	251
7.1	Iteration Algorithm	253
7.2	Canonical Representation	256
7.2.1	Recurrence Formula	258
7.2.2	Canonical Representation of the Path Deviations	259
7.3	Expansion Polynomials of the Variational Function	261
7.4	Path Equation Approach	264
7.4.1	Primary Deviations	266

7.5	Second-Rank Path Deviations of Systems with Midsection Symmetry	267
7.5.1	Wien Filter	268
7.5.2	Magnetic Systems	271
7.6	Second-Rank Path Deviations of Systems with Straight Axis	273
7.6.1	Second-Order Path Deviation	275
8	Aberrations	281
8.1	Second-Rank Aberrations	284
8.1.1	Systems with Midsection Symmetry	285
8.1.2	Systems with Straight Optic Axis	289
8.1.3	Axial Chromatic Aberration and Chromatic Distortion	291
8.2	Third-Order Aberrations of Systems with Straight Axis	295
8.2.1	Structure of the Geometrical Eikonal Polynomials	295
8.3	Geometrical Aberrations of Round Lenses	297
8.3.1	Scherzer Theorem	303
8.3.2	Spherical Aberration and Disc of Least Confusion	304
8.3.3	Coma	306
8.3.4	Image Curvature	308
8.3.5	Field Astigmatism	310
8.3.6	Distortion	312
8.4	Primary Aberrations of Glaser's Magnetic Model Lens	313
8.5	Geometrical Aberrations of Quadrupole–Octopole Systems	315
8.5.1	Aperture Aberration of Stigmatic Orthogonal Quadrupole Systems	317
8.5.2	Aberrations Introduced by Octopoles	319
8.5.3	Third-Order Aberrations of Systems with Threefold Symmetry Corrected for Second-Order Aberrations	320
8.5.4	Parasitic Aberrations	322
8.6	Fifth-Order Aberrations of Orthogonal Systems with Straight Axis	327
8.6.1	Fifth-Order Aperture Aberration of Achromatic Third-Order Aplanats	329
9	Correction of Aberrations	333
9.1	Correction of Chromatic Aberrations	336
9.1.1	First-Order Wien Filter	336
9.1.2	Correction of Chromatic Distortions	339
9.1.3	Electrostatic Correction of Chromatic Aberration	342
9.1.4	Chromatic Correction of Systems with Curved Axis	347
9.1.5	Correction of Second-Degree Dispersion	354
9.2	Correction of Geometrical Aberrations	356
9.2.1	Correction of Second-Order Aberrations	356
9.2.2	Correction of Third-Order Spherical Aberration	362

9.2.3	Aplanats	364
9.2.4	Achromatic Aplanats	367
9.2.5	Correction of Third-Order Field Curvature and Field Astigmatism	376
9.2.6	Correction of Coma.....	380
10	Electron Mirrors	387
10.1	Reference Electron	388
10.2	Equation of Motion	389
10.3	Eikonal Approach	391
10.4	Rotationally Symmetric Mirrors	393
10.4.1	Linear Approximation	394
10.4.2	Lateral Fundamental Rays	395
10.4.3	Longitudinal Fundamental Deviations.....	395
10.5	Path Deviations	401
10.6	Electrostatic Mirror	404
10.6.1	Positional Deviations	404
10.6.2	Axial Aberrations	405
11	Optics of Electron Guns	413
11.1	Field Emission Guns	414
11.2	Gaussian Optics	416
11.3	Aberrations	418
11.3.1	Second-Rank Deviations	419
11.3.2	Third-Order Spherical Aberration at the Crossover.....	421
12	Confinement of Charged Particles	425
12.1	Paul Trap.....	425
12.2	Combined Trap	427
13	Monochromators and Imaging Energy Filters	429
13.1	Electrostatic Monochromator	430
13.2	Imaging Energy Filters	432
13.2.1	Types of Imaging Energy Filters	433
13.2.2	MANDOLINE Filter	435
13.2.3	W-Filter	439
14	Relativistic Electron Motion and Spin Precession	443
14.1	Covariant Hamilton Formalism	446
14.2	Propagation in Minkowski Space.....	451
14.2.1	Path Equation	451
14.2.2	Hamiltonian	452
14.2.3	Propagation of Free Particles in Minkowski Space	456
14.3	Four-Dimensional Hamilton–Jacobi Equation	460
14.4	Relativistic Maupertuis Principle	463
14.5	Approximate Relativistic Canonical Momentum and Hamiltonian in the Laboratory System	467

14.6	Spin Precession	469
14.7	Stern–Gerlach Effect Revisited	474
15	Electron Self-Action	477
15.1	Electromagnetic Field of the Moving Electron	478
15.1.1	Field of an Electron Moving with Constant Velocity	481
15.2	Radiation Field Emitted by the Accelerated Electron	482
15.2.1	Dipole Approximation.....	485
15.2.2	Radiation Field of the Moving Electron	486
	References	489
	Nomenclature	495
	Index	497